

PRESSURE SENSITIVE ELEMENT

Patent Number: JP9213168
Publication date: 1997-08-15
Inventor(s): KOIZUMI SATOSHI; OOI YOSHIKAZU; AIHARA SUSUMU
Applicant(s): TEIKOKU TSUSHIN KOGYO CO LTD
Requested Patent: ☐ JP9213168
Application Number: JP19960040681 19960202
Priority Number(s):
IPC Classification: H01H13/52 ; H01C10/10 ; H01H13/00 ; H01L29/84
EC Classification:
Equivalents: JP3143858B2

Abstract

PROBLEM TO BE SOLVED: To provide a pressure sensitive element in which thickness is made to be thin, manufacturing is facilitated, and no occurrence of failure resulting from an assembling error is allowed.
SOLUTION: A pressure sensitive element is composed of a pressure sensitive film element 20 formed in the center of the bottom face of the dome-like pushing portion 11 of a film 10. The pressure sensitive film element 20 is composed of an electrode pattern 21 formed on the face of the film 10, a pressure sensitive resistant film 25 formed on the electrode pattern 21, an electrode pattern 27 formed on a location opposite to the electrode pattern 21 on the pressure sensitive resistant film 25.

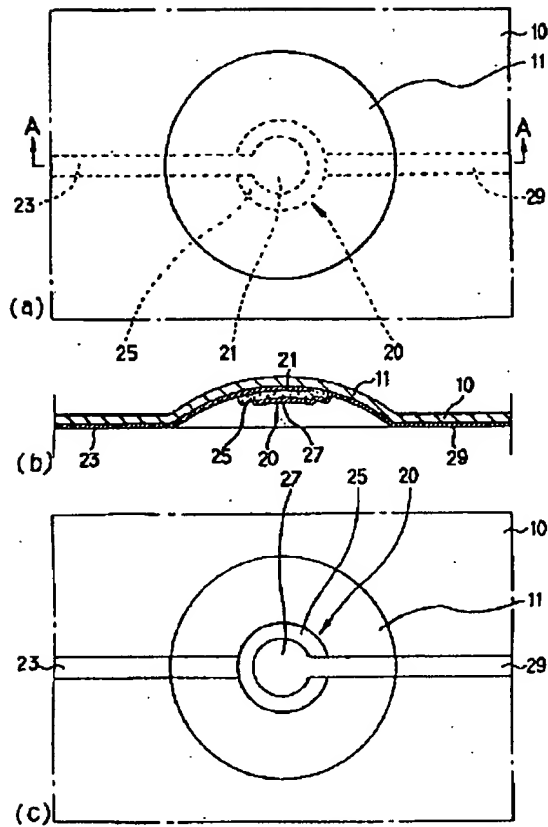
Data supplied from the esp@cenet database - l2

25 感圧抵抗膜

41-4 導電パターン

31-5 基板(基材)

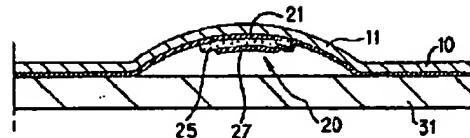
【図1】



10 フィルム 20 感圧膜素子 21, 27 電極パターン 25 感圧抵抗膜

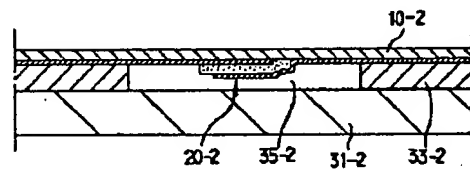
本発明の感圧素子を示す図

【図2】



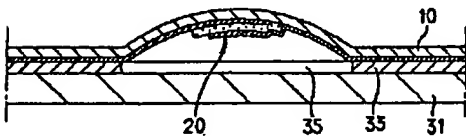
1 使用例を示す図

【図5】



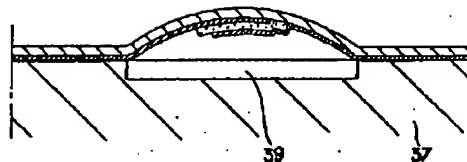
他の感圧素子の1使用例を示す図

【図3】



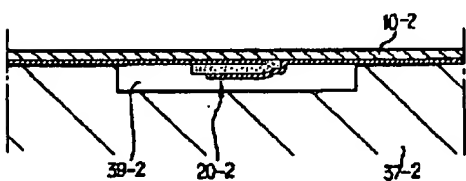
1 使用例を示す図

【図4】



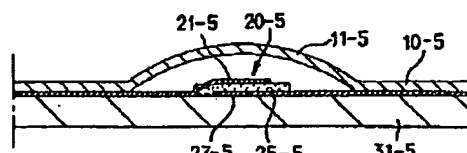
1 使用例を示す図

【図6】



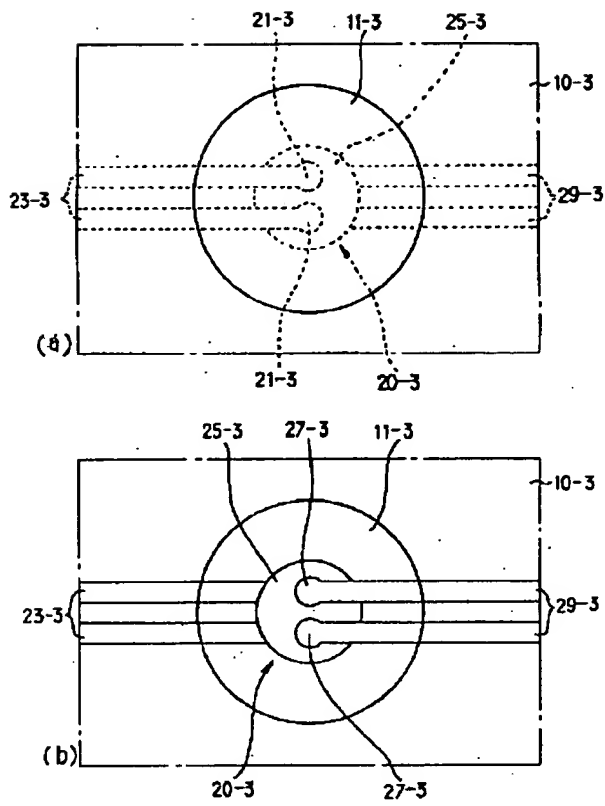
他の感圧素子の1使用例を示す図

【図9】



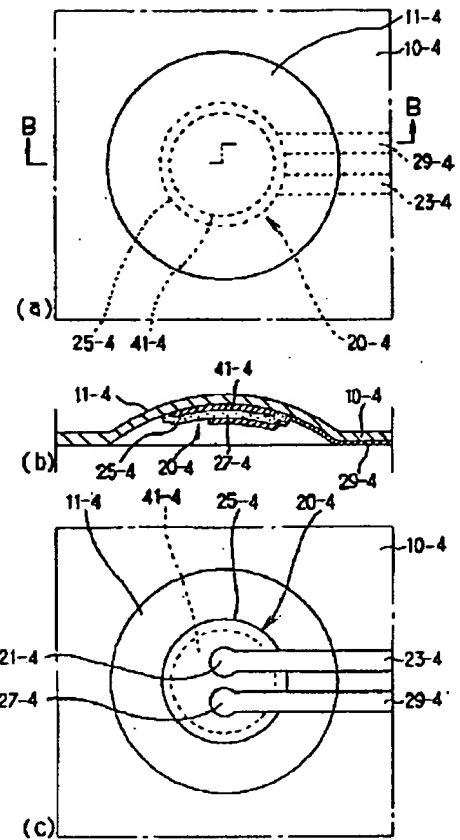
他の感圧素子を示す図

【図7】



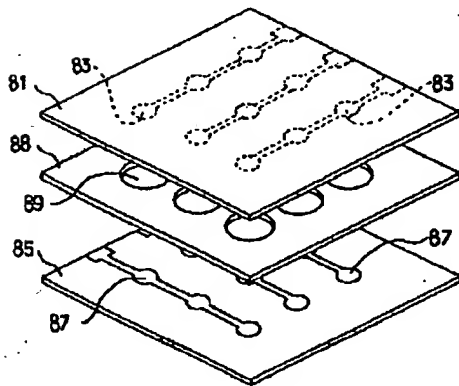
他の感圧素子を示す図

【図8】



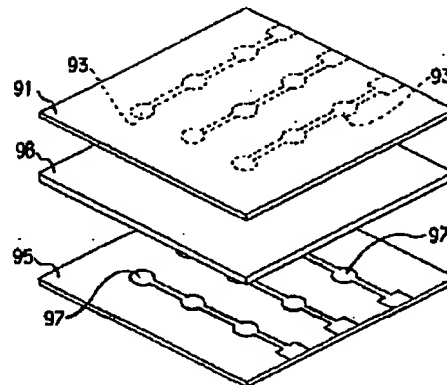
他の感圧素子を示す図

【図10】



従来のメンブレン型スイッチを示す図

【図11】



従来のメンブレン型スイッチを示す図